

ABSTRACT

**METHOD AND SYSTEM FOR PROVIDING ULTRAPURE WATER WITH
FLEXIBLE LAMP CONFIGURATION**

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A method and system of providing ultrapure water for semiconductor fabrication operations is provided. The water is treated by utilizing a free radical scavenging system. The free radical scavenging system can utilize actinic radiation with a free radical precursor compound, such as ammonium persulfate. The ultrapure water may be further
10 treated by utilizing ion exchange media and degasification apparatus. A control system can be utilized to regulate a continuously variable intensity of the actinic radiation.

[FIG. 2]